PATENT ABSTRACTS OF JAPAN

(11)Publication number:

11-162808

(43) Date of publication of application: 18.06.1999

(51)Int.CI.

H01L 21/027

B05C 11/08 // G03F 7/16

(21) Application number: **09-323261**

(71)Applicant: TOPPAN PRINTING CO LTD

(22) Date of filing:

25.11.1997

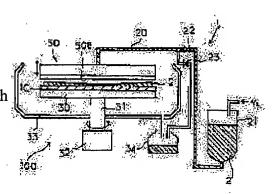
(72)Inventor: FUJITA YUICHI

(54) COATING FLUID SUPPLY APPARATUS FOR SPIN COATING APPARATUS

(57) Abstract:

PROBLEM TO BE SOLVED: To provide a fluid supply apparatus for a spin coating equipment which has excellent uniformity of a coating thickness on a substrate and a limits coating liquid consumption to minimum by a spin coating method, in which a photoresist and the like are coated in manufacturing a color filter for liquid crystal display and the like.

SOLUTION: A slot-extruded coating liquid supply apparatus 1, which discharges curtain-like coating onto a substrate which is spinning slowly, comprises a slotted coating liquid supply head 50 which allows discharge of the coating liquid 2 to continuously increase from the center to the periphery of the substrate 10, a slit width of the head 50 is continuously enlarged from the center to both sides and a slit distance between a manifold provided inside the head 50 and an end 50e of the head is reduced from the center to both ends.



LEGAL STATUS

[Date of request for examination]

10.09.2001

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

Moto of autimation of minht